

# Chia-Yu Hsu

## List of Publications by Year in descending order

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Version: 2024-02-01

17  
papers

630  
citations

840776

11  
h-index

940533

16  
g-index

17  
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docs citations

17  
times ranked

356  
citing authors

#	ARTICLE	IF	CITATIONS
1	Ensemble convolutional neural networks with weighted majority for wafer bin map pattern classification. <i>Journal of Intelligent Manufacturing</i> , 2022, 33, 831-844.	7.3	29
2	Data Visualization of Anomaly Detection in Semiconductor Processing Tools. <i>IEEE Transactions on Semiconductor Manufacturing</i> , 2022, 35, 186-197.	1.7	6
3	Key Feature Identification for Monitoring Wafer-to-Wafer Variation in Semiconductor Manufacturing. <i>IEEE Transactions on Automation Science and Engineering</i> , 2022, 19, 1530-1541.	5.2	6
4	A New Double Exponentially Weighted Moving Average Run-to-Run Control Using a Disturbance-Accumulating Strategy for Mixed-Product Mode. <i>IEEE Transactions on Automation Science and Engineering</i> , 2021, 18, 1846-1860.	5.2	17
5	Multiple time-series convolutional neural network for fault detection and diagnosis and empirical study in semiconductor manufacturing. <i>Journal of Intelligent Manufacturing</i> , 2021, 32, 823-836.	7.3	78
6	A two-phase non-dominated sorting particle swarm optimization for chip feature design to improve wafer exposure effectiveness. <i>Computers and Industrial Engineering</i> , 2020, 147, 106669.	6.3	3
7	A Review on Fault Detection and Process Diagnostics in Industrial Processes. <i>Processes</i> , 2020, 8, 1123.	2.8	112
8	An Autoencoder Gated Recurrent Unit for Remaining Useful Life Prediction. <i>Processes</i> , 2020, 8, 1155.	2.8	31
9	Defective wafer detection using a denoising autoencoder for semiconductor manufacturing processes. <i>Advanced Engineering Informatics</i> , 2020, 46, 101166.	8.0	34
10	L-measure evaluation metric for fake information detection models with binary class imbalance. <i>Enterprise Information Systems</i> , 2020, , 1-20.	4.7	0
11	Data-Driven Approach for Fault Detection and Diagnostic in Semiconductor Manufacturing. <i>IEEE Transactions on Automation Science and Engineering</i> , 2020, 17, 1925-1936.	5.2	81
12	Similarity matching of wafer bin maps for manufacturing intelligence to empower Industry 3.5 for semiconductor manufacturing. <i>Computers and Industrial Engineering</i> , 2020, 142, 106358.	6.3	39
13	Clustering Ensemble for Identifying Defective Wafer Bin Map in Semiconductor Manufacturing. <i>Mathematical Problems in Engineering</i> , 2015, 2015, 1-11.	1.1	13
14	Integrated data envelopment analysis and neural network model for forecasting performance of wafer fabrication operations. <i>Journal of Intelligent Manufacturing</i> , 2014, 25, 945-960.	7.3	6
15	Data Mining for Optimizing IC Feature Designs to Enhance Overall Wafer Effectiveness. <i>IEEE Transactions on Semiconductor Manufacturing</i> , 2014, 27, 71-82.	1.7	31
16	Overall Wafer Effectiveness (OWE): A novel industry standard for semiconductor ecosystem as a whole. <i>Computers and Industrial Engineering</i> , 2013, 65, 117-127.	6.3	39
17	Semiconductor fault detection and classification for yield enhancement and manufacturing intelligence. <i>Flexible Services and Manufacturing Journal</i> , 2013, 25, 367-388.	3.4	105